

**Notice of References Cited**

Application/Control No.

09/657,055

Applicant(s)/Patent Under

Reexamination

FUKIAGE, NORIAKI

Examiner

Hung K. Vu

Art Unit

2811

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**U.S. PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-			
	B	US-			
	C	US-			
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**FOREIGN PATENT DOCUMENTS**

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**NON-PATENT DOCUMENTS**

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Gesheva et al., "Deposition of Characterization of CVD-Tungsten and Tungsten Carbonitrides on (100) Si", Ceramics International 22, 1996, pp. 87-89.
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\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
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